



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): MATSUT

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Examiner: SHAKERI, H.

Title: METHOD AND APPARATUS FOR
MECHANO CHEMICAL
POLISHING

Assistant Commissioner for Patents
Washington, D.C. 20231

Date: April 8, 2002

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KERRY S. CULPEPPER

CERTIFICATE OF HAND DELIVERY

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Typed Name: KERRY S. CULPEPPER

Signature: Kerry S Culpepper

AMENDMENT

Sir:

In response to the Office Action mailed November 6, 2001, please enter the following amendments and consider the appended remarks.

IN THE CLAIMS

Please cancel claims 1 – 43 without prejudice.

Please add the following new claims:

44. (New) A method for mechanochemical polishing comprising:

preparing abrasive grains made of chromium (III) oxide; and

polishing a surface of a semiconductor wafer by mechanochemical polishing using the

abrasive grains; and